HITACHI
Inspire the Next

自動角度可変測定システムの紹介

日立紫外可視赤外分光光度計 UH4150

Automatic Variable Angle Absolute Reflectance Measurement System

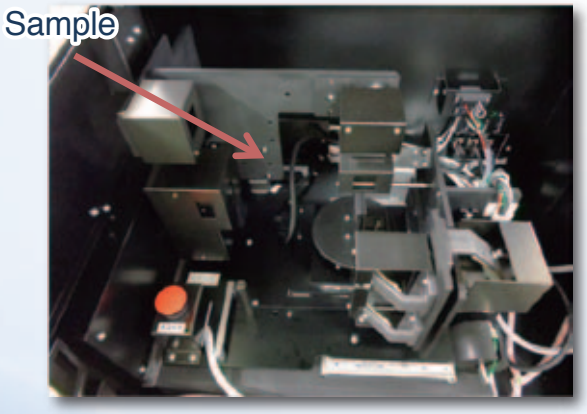
Science for a better tomorrow

特　長　～Feature～

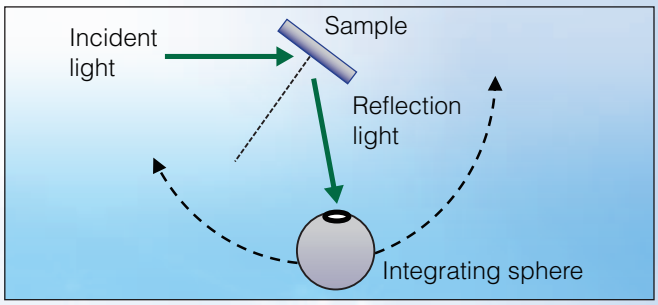
- **任意の入射角度における試料の透過･反射スペクトルの測定が可能**
  It is possible to measure absolute reflectance and transmittance at designated angle.
- **手動と比較し、試料の設置などに関わる時間を約9割削減**
  Setting time of the sample is reduced about 90% compared to manual operation.
- **試料の付け替えをせずに、同一箇所のS,P偏光測定が可能**
  It is possible to measure S and P polarization at the exact same spot of the sample without sample resetting.

UH4150

測　定　～Measurement～



自動角度可変測定システム
Automatic Variable Angle Absolute Reflectance Measurement System

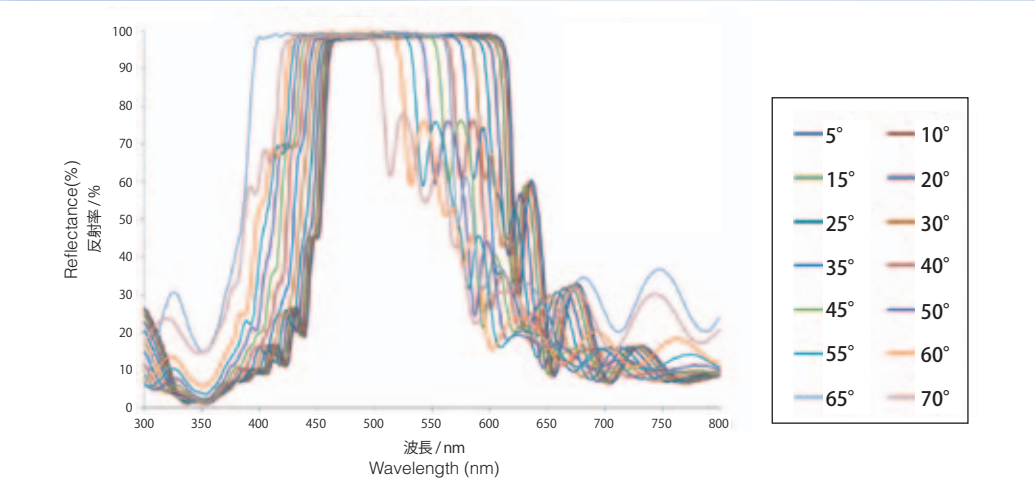


測定イメージ
Measurement image

<Specification>

Wavelength	: 240～2600 nm
Angle %T	: 0～70°
%R	: 5～70°
Sample size	: 30 × 30～130 × 130 mm
Sample thickness	: Less than 10 mm

- **入射角度の変化による光学薄膜の反射スペクトルの変化**　Thin film measurement by variable incident angle



入射角度の変化による反射スペクトル(S､P偏光の平均)測定結果
Thin film's Reflectance Spectrum (S and P polarization average) by variable incident angle

※ 装置･付属装置の外観等は予告なく変更される場合があります。